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TITLE: PLASMA PROCESSING APPARATUS

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INVENTOR-INFORMATION:

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ABSTRACT:

PROBLEM TO BE SOLVED: To obtain a plasma processing apparatus which can prevent an inner surface of a container from wearing.

SOLUTION: A limiting plate 91 is disposed between an inner wall of a processing chamber 31 and a microwave guide window 34, and the plate 91 is formed therein with an opening 81 through which the window 34 is exposed to the chamber 31. Consequently, a leakage electric field from the window 34 can advance into the chamber 31 via the opening 81 and generates a plasma in the chamber 31.

Further, since the plasma is away from the inner wall of the chamber 31, the inner wall of the chamber 31 can be prevented from wearing.

In addition, since a part of the window 34 opposed to the plate 91 is coated with a conductive FILM 96, unnecessary discharging between the window 34 and plate 91 can be

avoided.

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